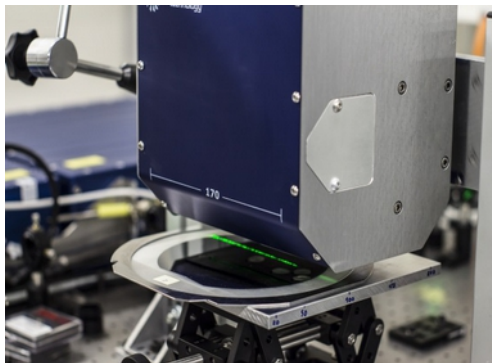
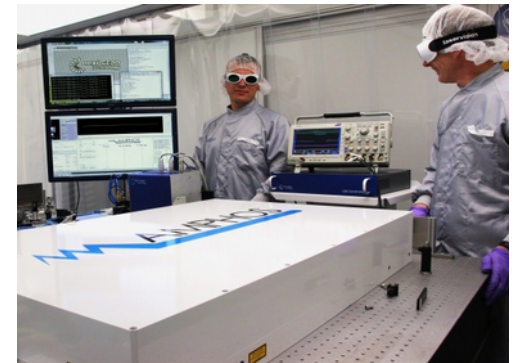
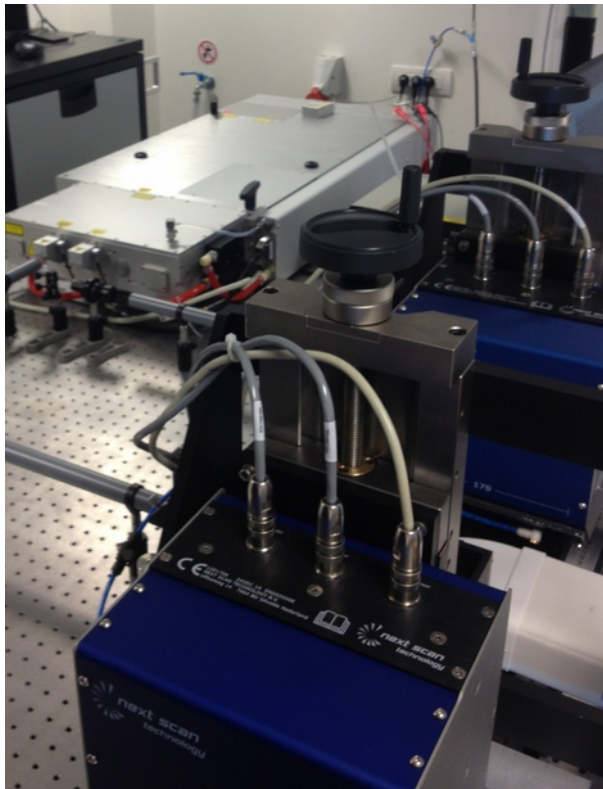
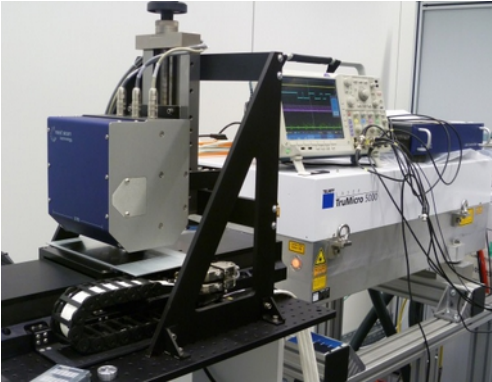


Polygon Scanners – Capabilities, Applications and System integration considerations

Lars Penning

CEO Next Scan Technology

Innovating and leading polygon scanner technology

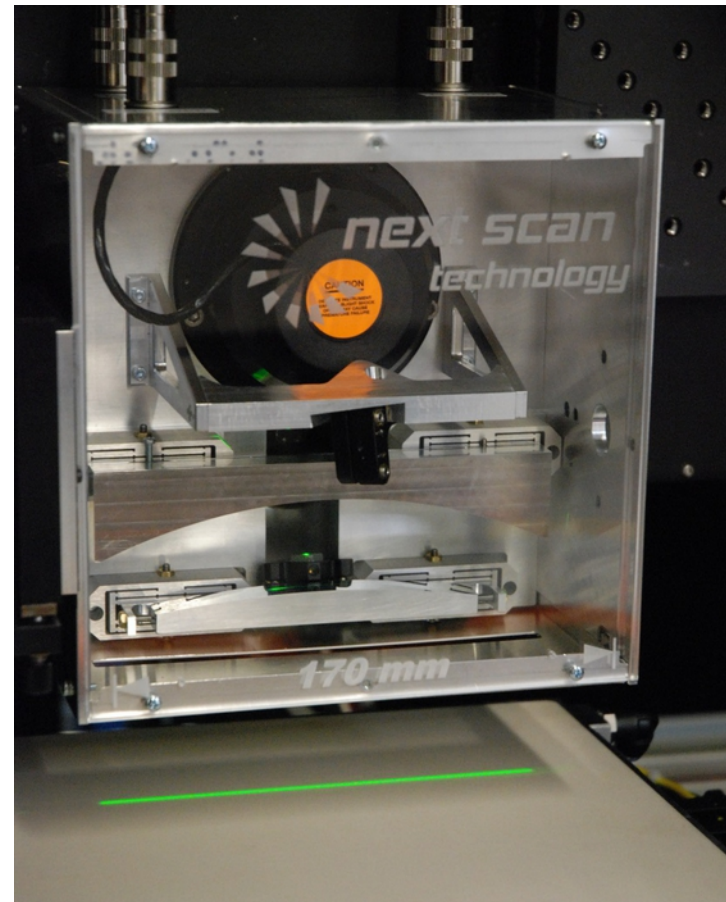


Introduced polygon scanner system at WOP11

Next Scan Technology was the first to introduce polygon based scanner systems to the laser micro-machining market.

Technology is similar to desktop laser printers, however, tailored for:

- Very high laser pulse power handling
- Very high resolution and accuracy
- High quality spot size
- Sophisticated USP laser/scanner synchronisation

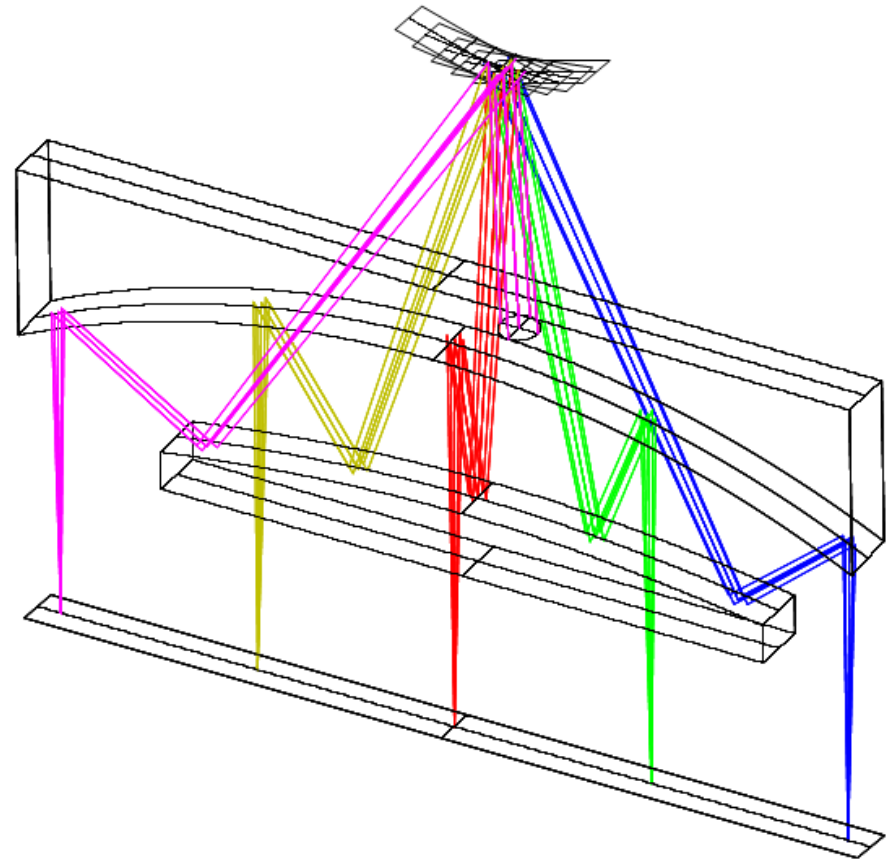


Patent pending two mirror optics

- Dual wavelength coating both IR and GR wavelengths, or specific UV version.
- High precision optics, very low distortion, line straightness $\pm 10 \mu\text{m}$
- Constant round spot size along scanned path down to $8 \mu\text{m}$ @ 355 nm
- Full telecentric up to 300 mm



Constant material-light
interaction



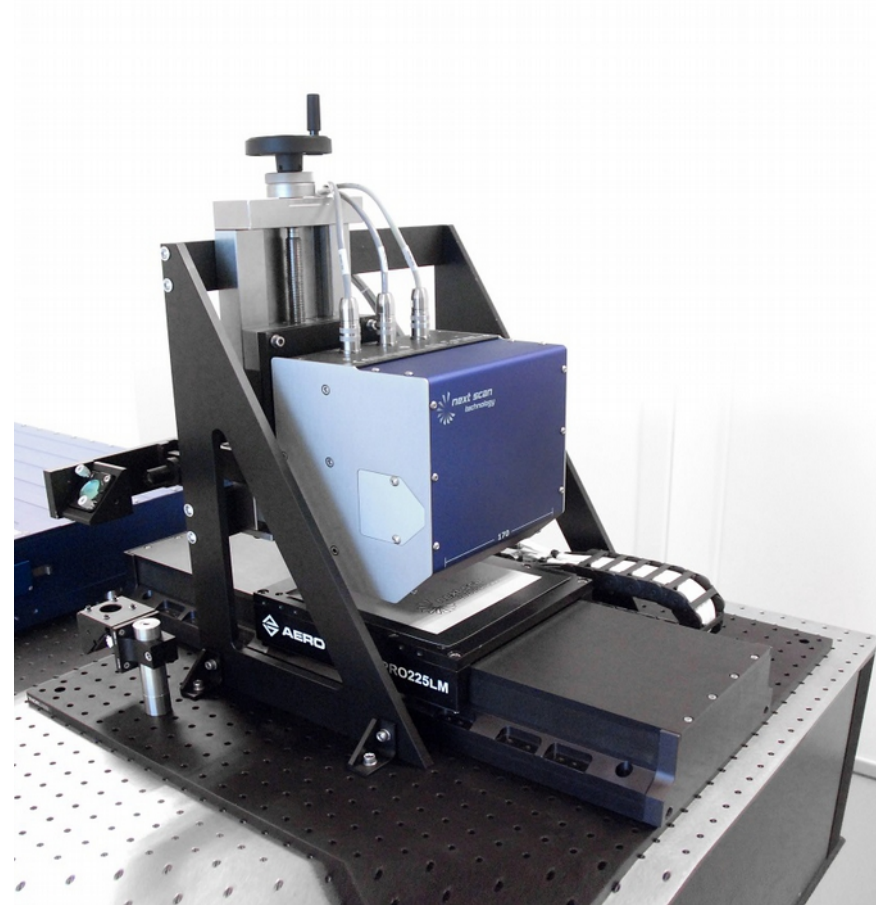
Commercial release LSE170

First commercially available polygon based scanner system on the market.

One box pre-aligned optical system.

Laser scan controller for easy integration by integrators and machine builders.

Proces Development kit for instant process development start.



Introduction LSE170HNA and LSE300

LSE170 HNA

170 mm scan width

Half the spot size of LSE170

LSE300

300 mm scan width

Same spot size as LSE170

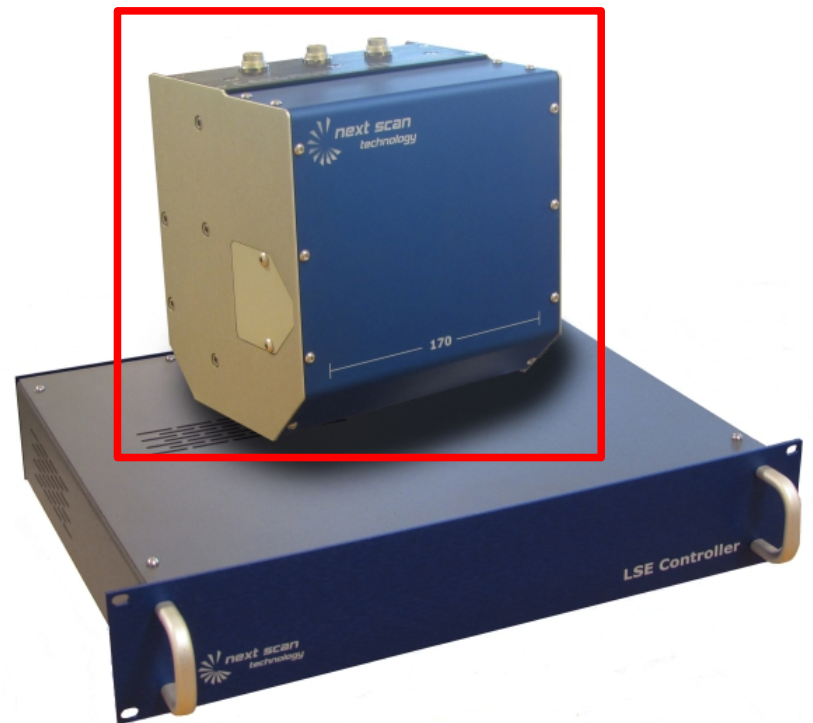
Both systems can be delivered with

SuperSync and TrueRaster options.



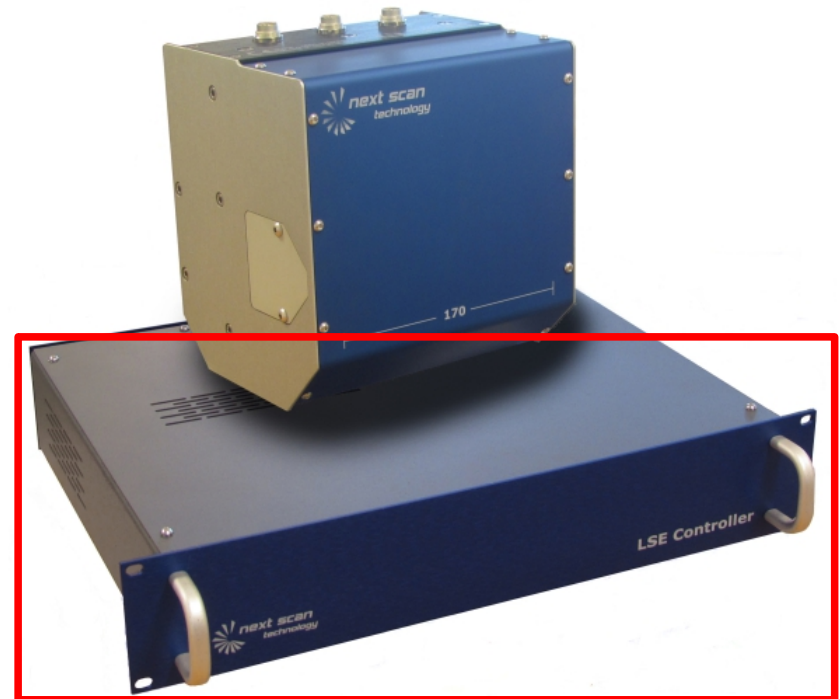
LSE scanner head

- Polygon and drive motor
- Input beam shaping optics
- Telecentric f-theta optics



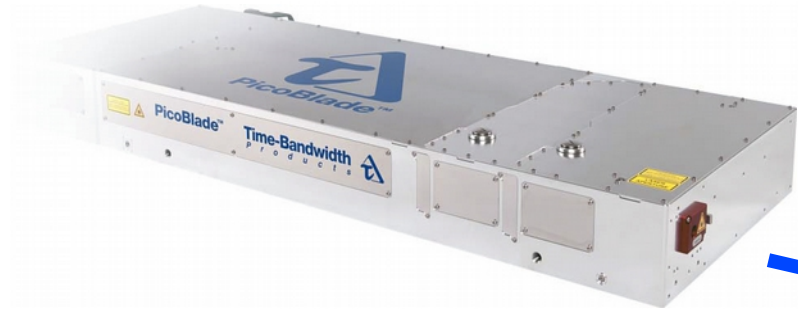
LSE controller

- Polygon speed control
- Ethernet communication port
- Linear transport interface
- Laser (SuperSync) interface



Typical set-up

CW or nano-,pico- or femtosecond pulsed laser source



LSE controller synchronises laser, scanner, stage and pattern data transfer

Scribe data stream



Stage or R2R by customer

Vector scanning

- Beam path fully programmable in 2D
- Scan speed may vary along path
- Mechanical start/stop per vector, speed is inertia limited, low inertia mirrors required
- Can be programmed in raster mode
- Processing time depends on nr of features

Often best fit for line mode patterns

Limited in speed

Raster scanning

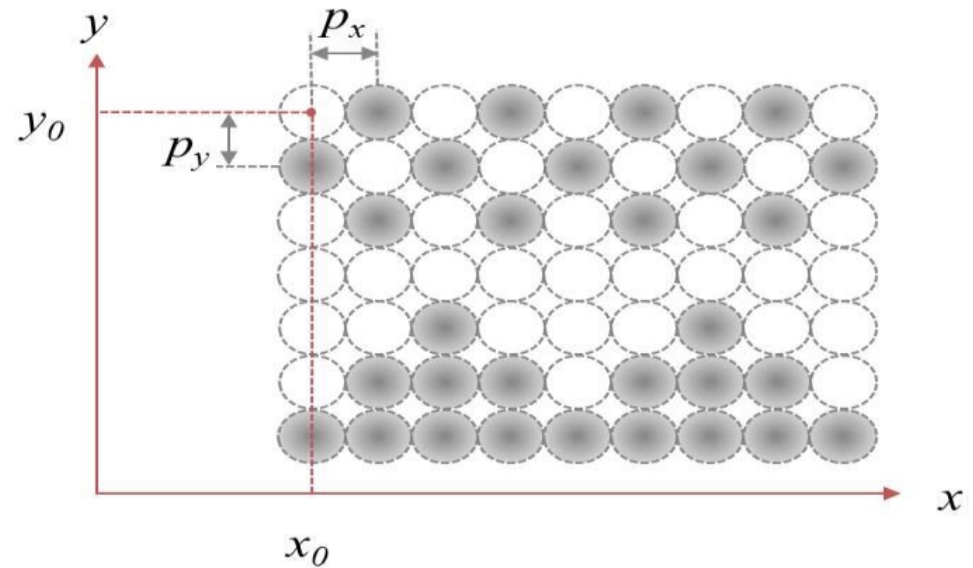
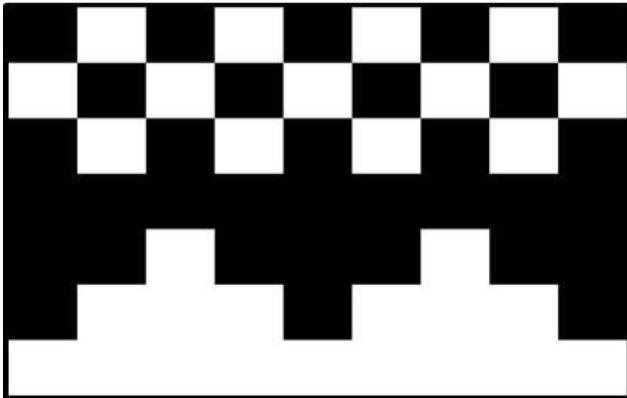
- Beam path is a semi fixed line pattern
- Scan speed is constant along path
- Constant motion device, high inertia needed for constant speed
- Hardware implementation of raster scan mode
- Fixed processing time but complexity for free

Best for dense patterns

High writing speeds possible

Laser pulse on grid position is controlled by monochrome bitmap

- Each laser pulse will be positioned on a pre-determined position which is the (user programmable) grid
- A rectangular region (bitmap, white is laser pulse) is formed by equally spaced parallel lines (line spacing)

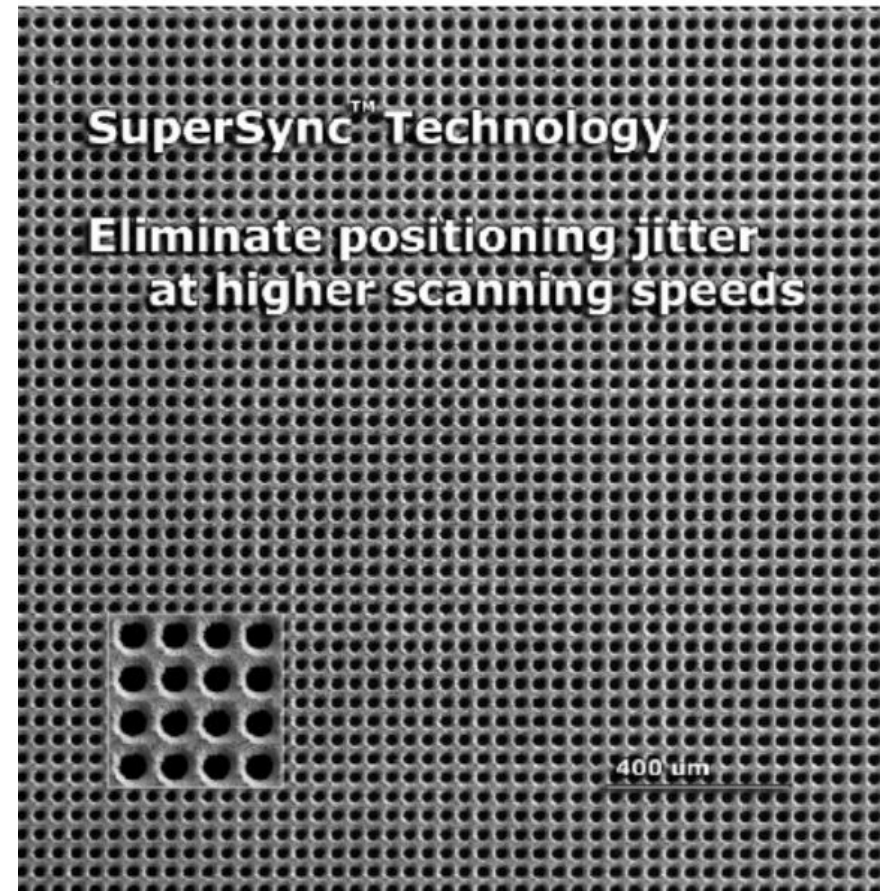


Percussion type drilling at very low 'pulse' rate

- Scan speed to separate the holes
- Application example
 - 400 Khz PRR
 - 250 um spot spacing through
 - 100 meters/sec is 400 lines/sec
 - 100 passes per hole is 4 lines/sec
 - 170 mm board is 600 holes per line

> 2.000 holes per second

Works with lower rep-rate lasers !

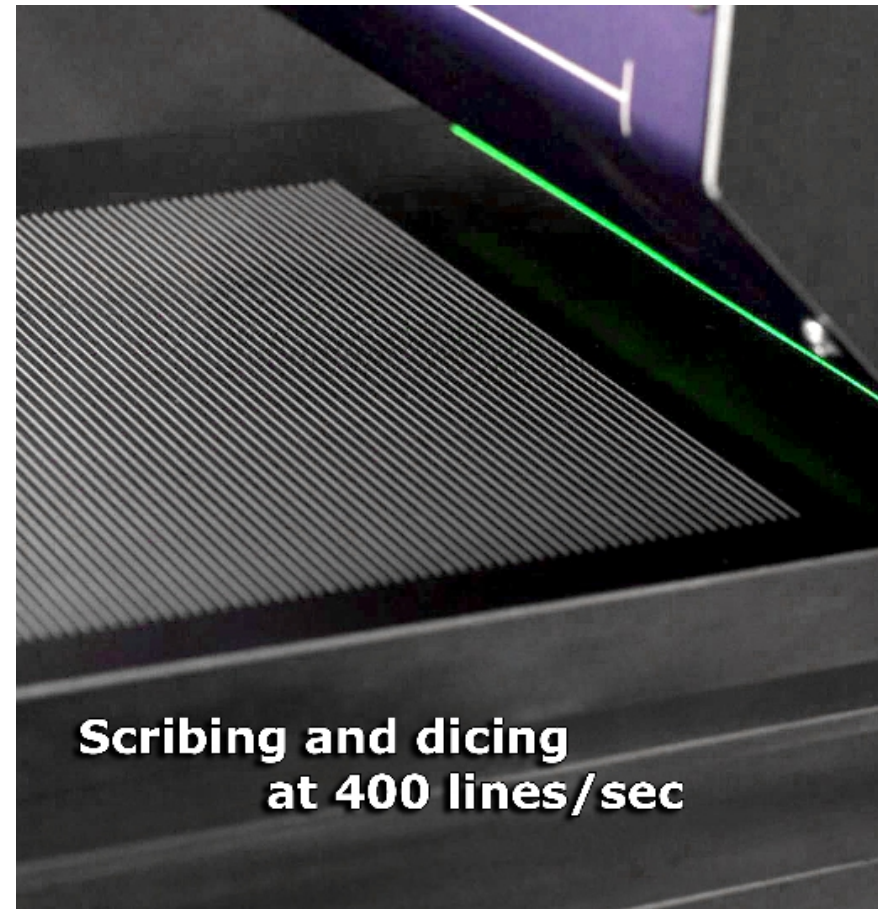


Scribing, grooving and dicing

- Speed set by PRR and spot spacing
- Linear stage in stepping mode or moves at constant speed.

Application example

- 2 MHz PRR
- 25 μm spot spacing
- 50 meters/sec (200 lines/sec)
- 40 passes/kerf
- 3 kerfs/second

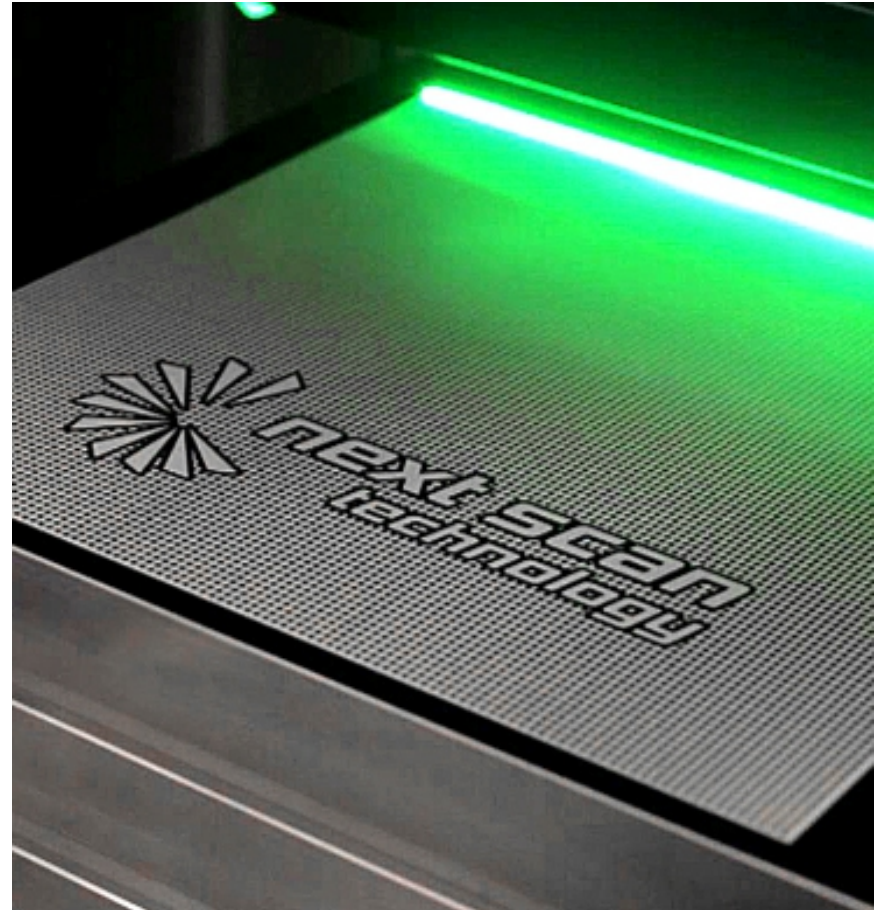


Apply any texture in same time!

- 100 meters/sec is 400 lines/sec
- Linear speed stage is 1 cm/s at 25 μm
- Surface speed is 17 cm^2/sec at 4 MHz
- Multi-pass for 'deeper' structures

Applications:

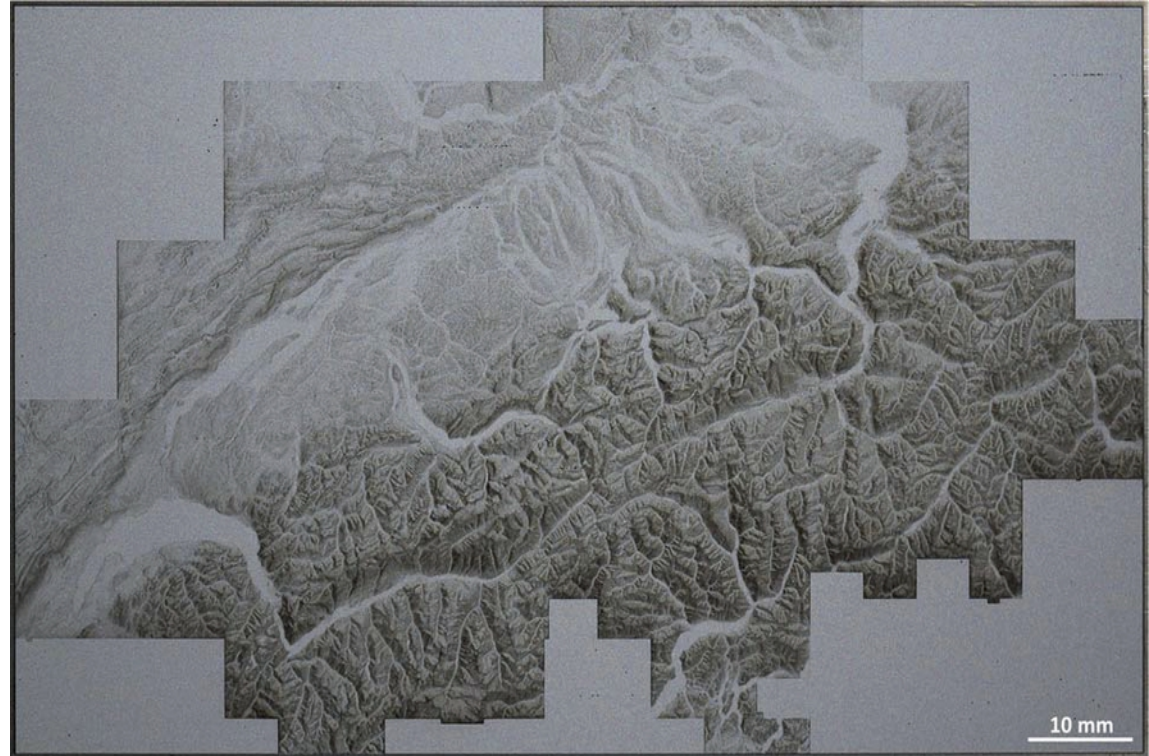
- Thin film patterning
- High density marking
- Volume ablation (holes/slots/pockets)
- Additive printing (LIFT, STL)
- Laser cleaning/annealing



Stainless steel engraving

This work was supported by the
FP7 project APPOLO

Bern University of Applied Sciences
B. Neuenschwander/B. Jäggi/M.
Zimmerman



Dimensions 108 x 65 mm

14.5 μm spot spacing (1.750 dpi)

4.1 MHz rep-rate* - 25.6 W

Scan speed 59,5 m/s

24 seconds per layer

2233 layers

Scanning strategy: start point dithering/averaging

Maximum depth about 100 μm

Modularity: only add the complexity on a real need basis

Do I need Laser pulse synchronisation?

What if my laser's rep rate laser is too low ?

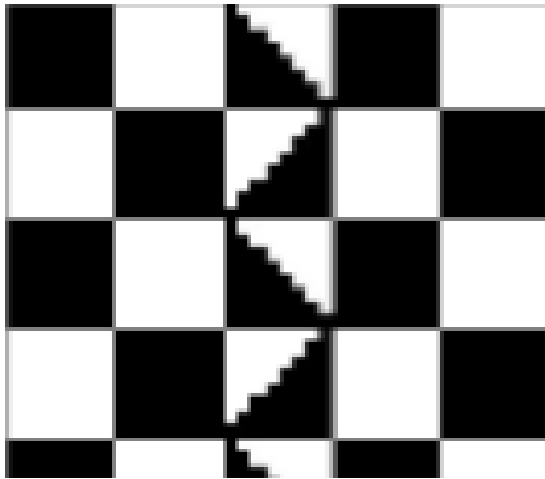
Do polygon facet errors harm my application ?

Repeatability is not enough, I need higher accuracy !

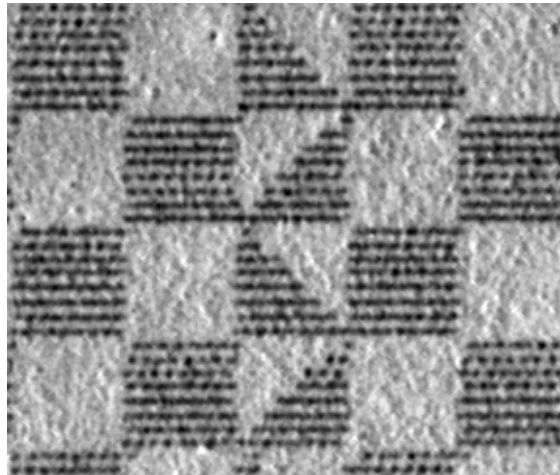
Proprietary SuperSync technology realises repeatable dot position

1 MHz @ 100 m/s scan speed is a 100 μm spot positioning error !!!

- SuperSync laser/scanner electronic synchronisation reduces jitter to few microns.

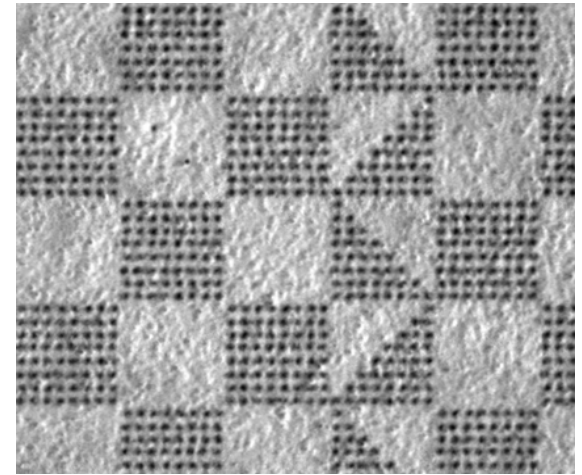


Bitmap pattern



No SuperSync™

Multi-pass operation at 100 m/s (10 passes)

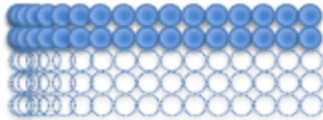


SuperSync™

Multi-pass operation at 100 m/s (10 passes)

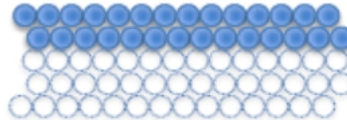
Processing quality versus laser/scanner synchronisation

"acceleration" problem



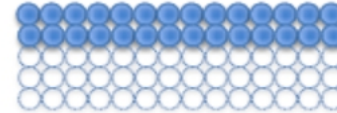
**Uncontrolled
processing quality at
ramp up/down**

Sky writing

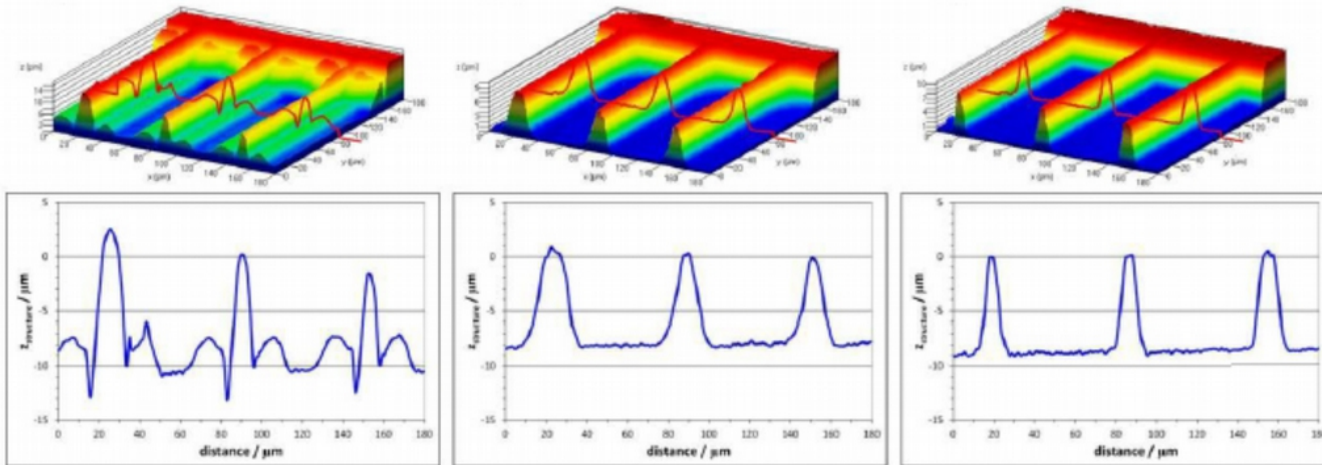


**Improved quality
at constant speed
with existing
timing jitter**

Synchronized



**Highest quality
at constant speed
through eliminated
timing jitter**

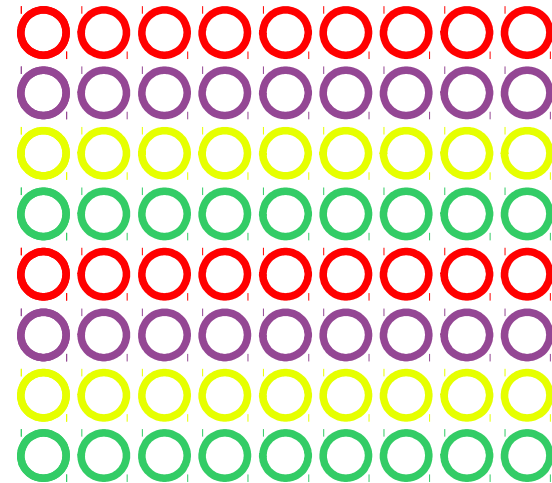


Courtesy Bern University Applied Sciences: Research by B. Neuenschwander/B. Jäggi/M. Zimmerman

Dot interleaving mode

- In dot-interleaving mode, the spot spacing is larger than the spot size (no overlap), so no heat accumulation

Bitmap data:



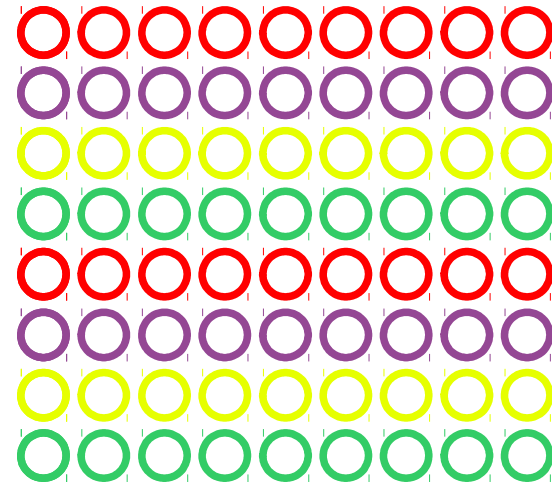
Scribed line pattern:



Dot interleaving mode

- In dot-interleaving mode, the spot spacing is larger than the spot size (no overlap), so no heat accumulation
- Successive lines in the bitmap are used to fill the gap between the laser pulses of the former passes.

Bitmap data:



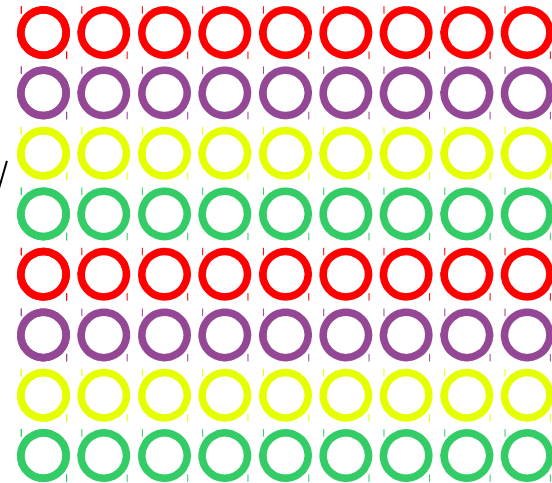
Scribed line pattern:



Dot interleaving mode

- In dot-interleaving mode, the spot spacing is larger than the spot size (no overlap), so no heat accumulation
- Successive lines in the bitmap are used to fill the gap between the laser pulses of the former passes.
- Overlapped regions are scribed with minimal one scan line time spacing


Bitmap data:



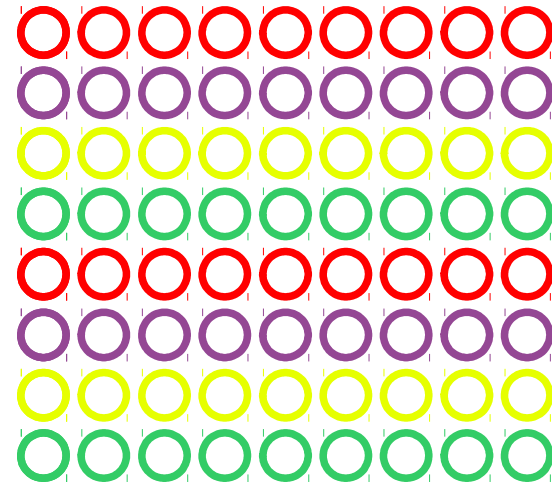
Scribed line pattern:



Dot interleaving mode

- In dot-interleaving mode, the spot spacing is larger than the spot size (no overlap), so no heat accumulation
 - Successive lines in the bitmap are used to fill the gap between the laser pulses of the former passes.
 - Overlapped regions are scribed with minimal one scan line time spacing
-  **Reduces thermal heating**

Bitmap data:

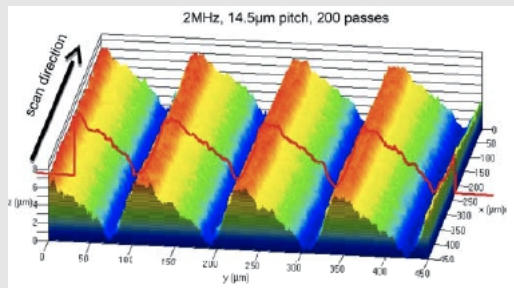


Scribed line pattern:

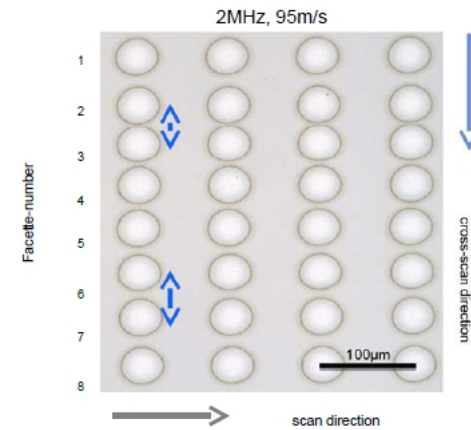
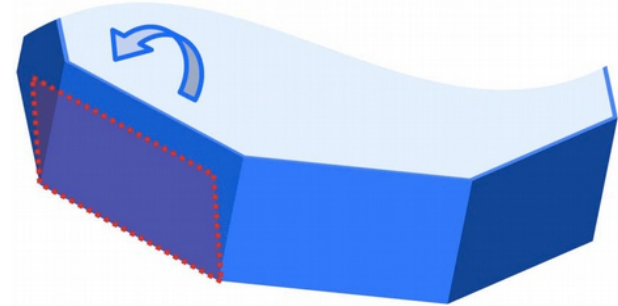
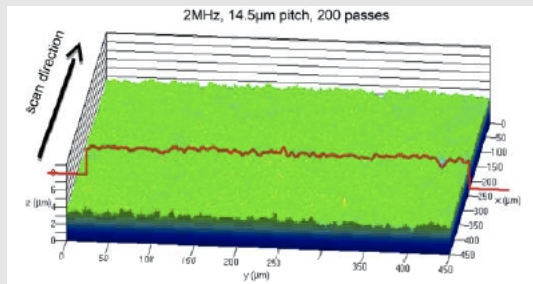


Avoiding Facet error related artifacts

- Pyramidal error affects processing quality when using **small** spot sizes



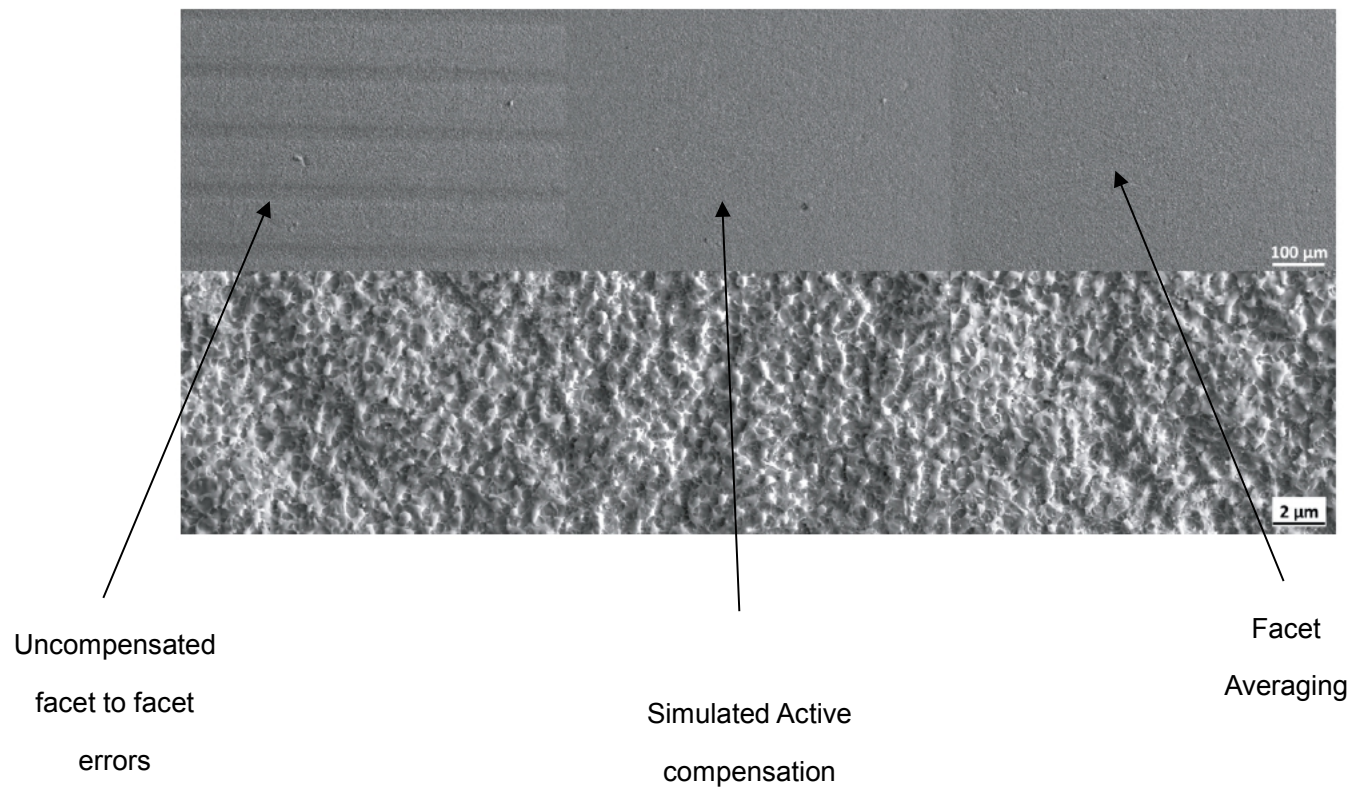
- Start layers with different facet as first line: averaging pyramidal error



No need for complex
correction

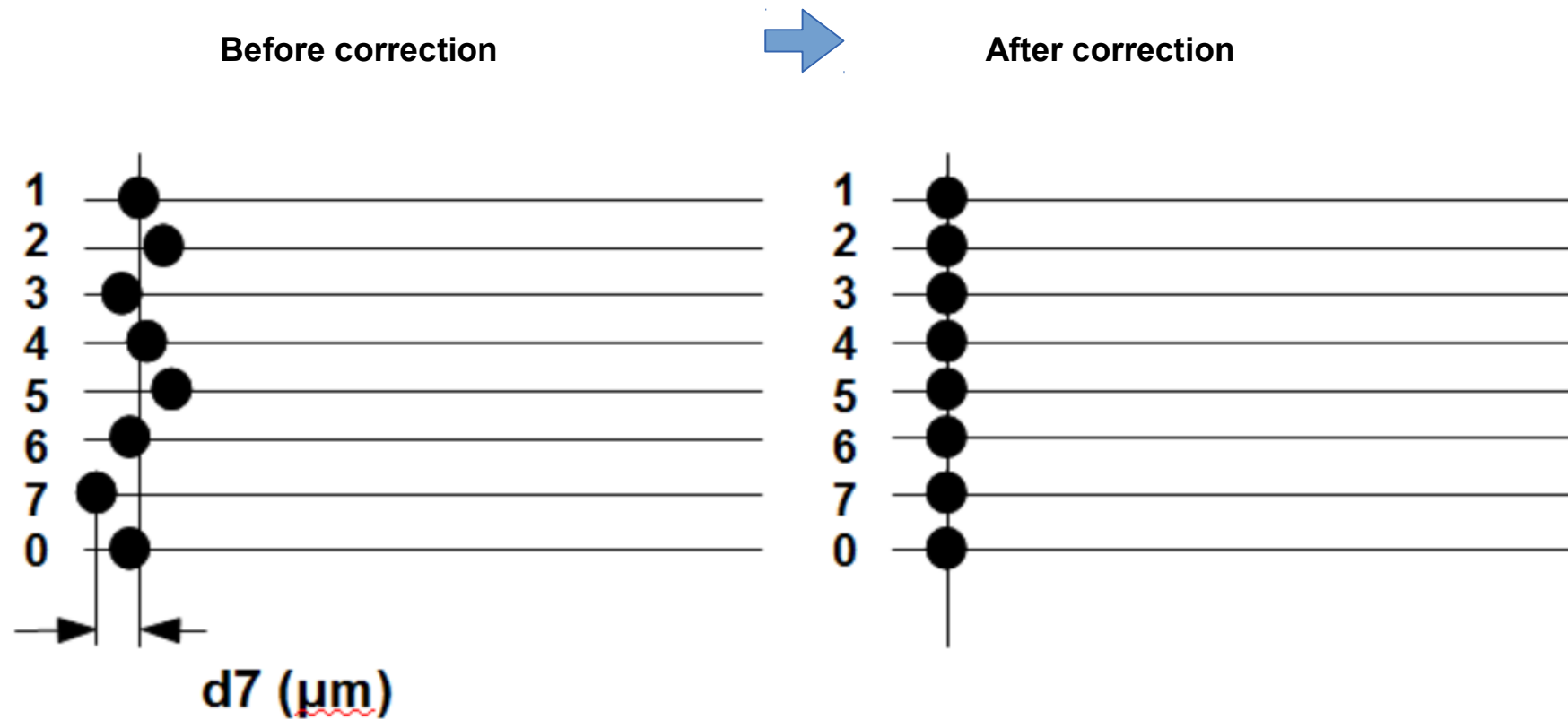
Layerwise multi-pass processing: Surface quality

Ablation at 2 MHz in stainless steel with 200 layers

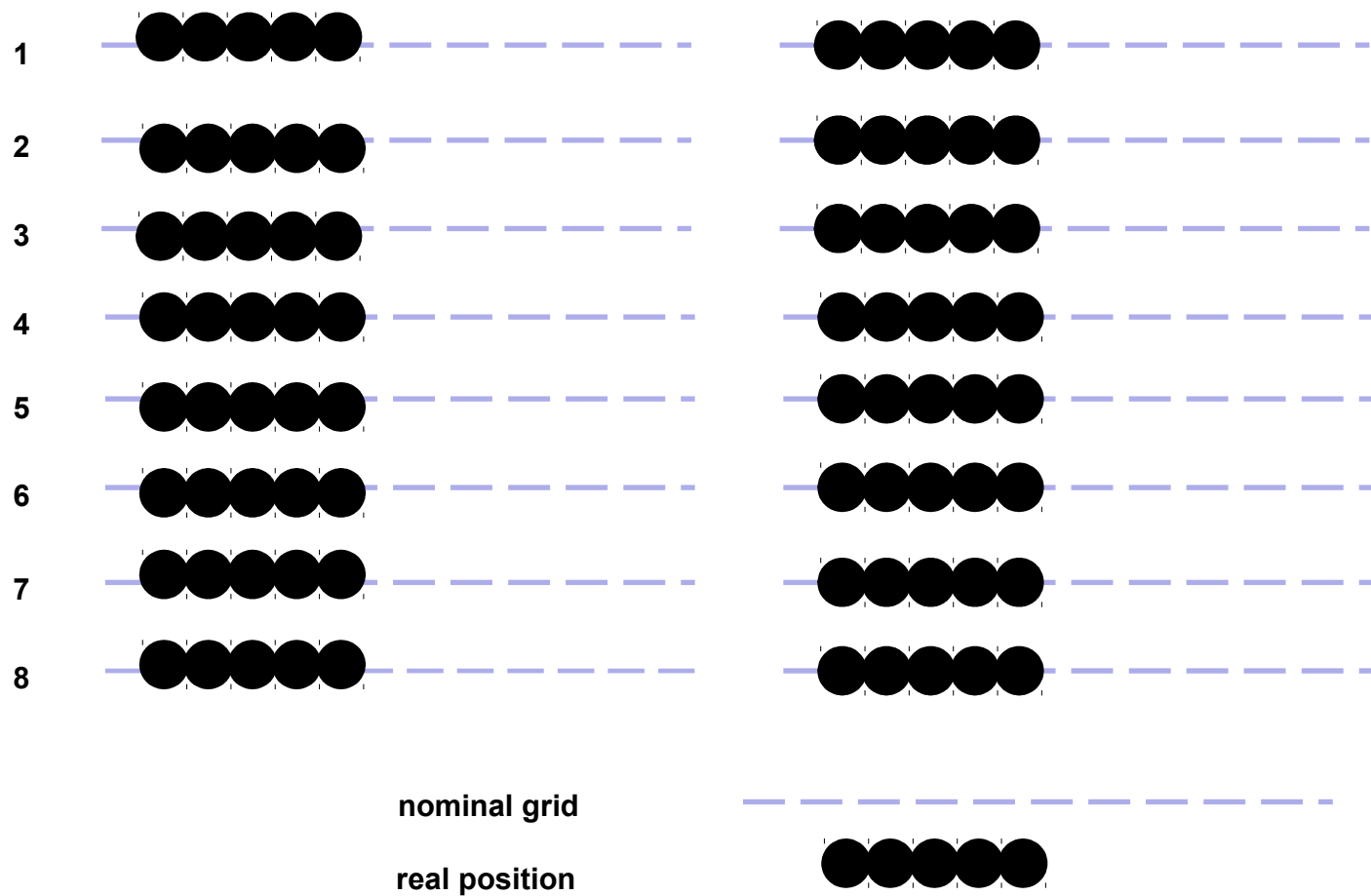


Standard Calibration

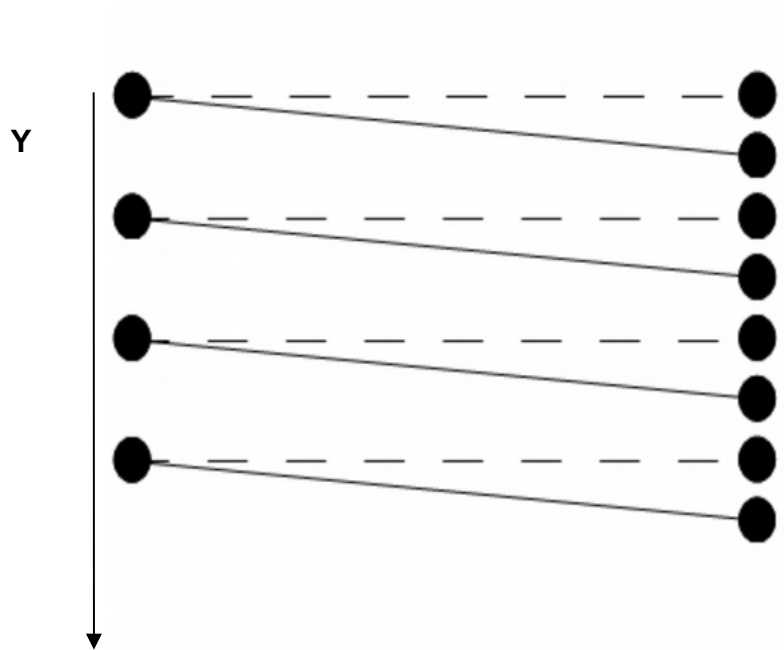
Facet start correction (in-scan)



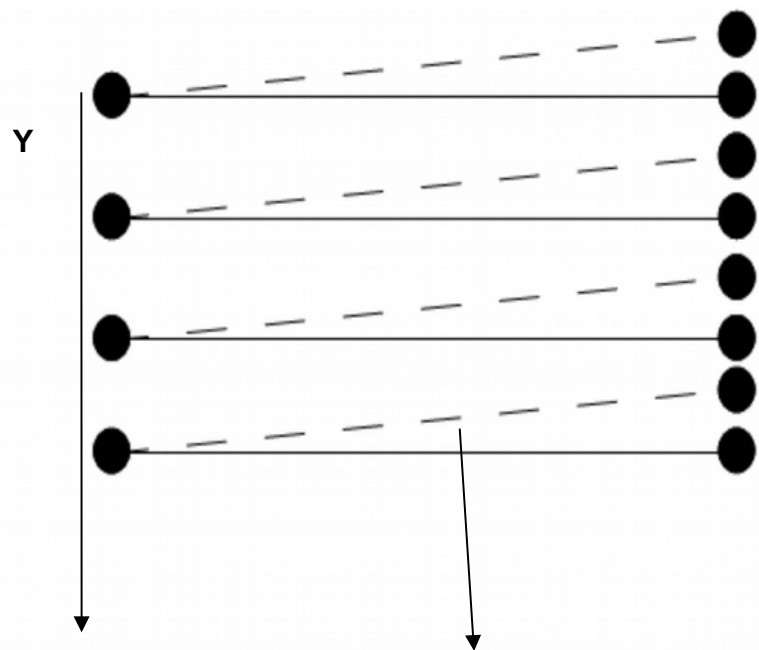
Scanner facet error elimination



Electronic Parallelogram distortion

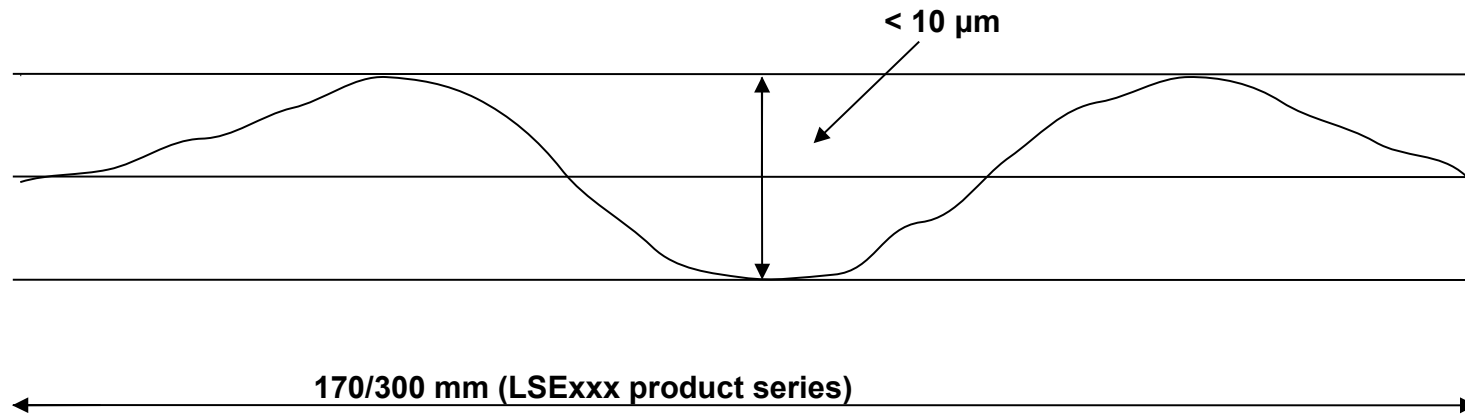


— — — = stationary line
————— = real scribe



Tilt scan head mechanically
versus stage direction (LSExxxSTD)

Scan Line Bow



**A repeatible Line bow is caused by f-theta 'lens' distortion
current line straightness is $\pm 10 \mu\text{m}$,
plus mirror manufacturing and alignment tolerances**

**TrueRaster Technology flattens line bow through calibration line
Distortion and reduces the line bow i.e. enabling a high line straightness**

NEW TrueCalib

TrueRaster has built-in real time drift compensation

Drift is measured 60-400 times/sec and compensates accordingly

This drift compensation also takes care of laser pointing stability

**(small changes in laser beam input angle versus scanner housing
also move focused spot in focal plane)**

Thank you for your attention

Come and see our products in hall 2 booth 423

LSE170HNA and LSE300STD development is supported by EU
FP7 programs:



and



Questions ?

